

ABSTRACT OF THE DISCLOSURE

5 The present invention is an apparatus for storing and delivering a low vapor
pressure process chemical to a process tool for semiconductor fabrication, comprising:
a) a bulk container for storing the process chemical; b) a process container for delivering
the process chemical to the process tool; c) a first manifold for delivering process
chemical from the bulk container to the process container; d) a solvent container
10 containing a quantity of solvent, and; e) a second manifold for delivering the process
chemical from the process container to a process tool. A process for using the
apparatus is also contemplated.

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